



635.43483X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: S. KADLEC, et al.

Serial No: 10/798,331

Filed: March 12, 2004

Title: METHOD FOR MANUFACTURING SPUTTER-COATED
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING
CHAMBER WITH SUCH SOURCE

Group: 1756

Examiner: n/a

SECOND PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 12, 2004

Sir:

The following amendments and remarks are submitted in the above-identified application.

Amendments to the Specification and Abstract

Amendments to the Claims

Remarks are included following the amendments